Transaction Information

Tool Status	Connected
Location	Asia
Wafer Size	300 mm
Fab Section	Lithography

General Product Information

Vendor Supplier	Nikon
Model	Nikon S208D
Vintage	2006
Asset Description	Nikon MainBody
Software Version	MCSW ver.180-P12/OCSW ver.180- P10
CIM	SECs
Process	Krf

Hardware Configuration (Fab)

System Type	Description	Quantity	Status
Main System	Main Body	1	OK
Handler System	External FOUP System	1	OK
Others			
Options System			
Factory Interface	SMIF	1	OK

Hardware Configuration (Subfab / Auxilliary Units)

Description	Quantity	Status
Amp Rack	1	OK
Gigaphoton Laser	1	OK
Temperature Controller	1	OK
Air Conditioner	1	OK

Missing/Faulty Parts / Accesorries List

Description	Quantity
NA	

Additional Tool Data Files

Reticle Blind		Setting value	44580
XM Outside		400 ~ 800 um	600
XP Inside		400 ~ 800 um	600
YM Outside		400 ~ 800 um	600
YP Inside		400 ~ 800 um	600
Lens performance Data			
Illumination Check		Setting value	44580
ID1	Uniformity	≤ 0.8 %	0.00251
	Power	> 3000 mw/cm2	4064
ID13	Uniformity	≤ 0.8 %	0.00212
	Power	> 3000 mw/cm2	3572
ID15	Uniformity	≤ 0.8 %	0.00235
	Power	> 3000 mw/cm2	3541
ID17	Uniformity	≤ 0.8 %	0.00474
	Power	> 3000 mw/cm2	3547
ID21	Uniformity	≤ 0.8 %	0.00315
	Power	> 3000 mw/cm2	3944
Wafer Stage Mirror Bow		Setting value	44580
Upper	Sub value X	≤ 8 nm	0.558
	Sub value Y	≤ 8 nm	0.573
Lower	Sub value X	≤ 8 nm	0.55
	Sub value Y	≤ 8 nm	0.602
Twist	Sub value X	≤ 8 nm	7.877
	sub value Y	≤ 8 nm	0.555
		Setting value	44580
Projection Lens Image Plane	Angle X	0 ± 1 urad	-0.015
	Angle Y	0 ± 3 urad	-0.204
Field Inclination TFD	max - min	≤ 0.080 um	0.045
	All reading have?	Yes / No	Yes
Flare check(Please inform EE when E0<=240mj)	E0	>=240 mj	300
Best Focus		0 ± 0.015 um	0.0132
Wafer Loader Repeatability (Front)		Setting value	44580
Y 3Sigma		≤ 15 um	9.653
Rot 3Sigma		≤ 200 urad	168.497
X 3Sigma		≤ 15 um	7.239
Rotation Mean		0 ± 200 urad	-35.627
Y mean		0 ± 10 um	3.075
X mean		0 ± 10 um	8.545
FIA Overlay Matching		Setting value	44580

Residual X 3Sigma		< 20nm	14.8
Residual Y 3Sigma		< 20nm	15.2
Plus/Minus Difference X		< 10nm	5.2
Plus/Minus Difference Y		< 10nm	3